



Simpler, faster, more robust

Insensitive to vibrations At-wavelength metrology Parallel optics testing





New metrology solution for easy at-wavelength testing of flat surfaces in any environment

MESO is the perfect tool for the characterization of:

- + Parallel Optics
- + Screens
- + Filters, dichroics
- + Mirrors
- + Beamsplitters
- + Windows, substrates
- + Corner cubes
- + Crystals
- + Rods, disks
- + Glass wafers
- + Displays
- + Machined surfaces
- + Windshields
- + Prisms
- + Large lenses
- + Optical systems, beam expanders

APPLICATIONS

- + In situ process control
- + Thin Parallel Optics characterization
- + Transmitted wavefront quality (TWE)
- + Surface shape & flatness measurement (RWE)
- + Large optics testing
- + Wedge measurement

FEATURES

- + Insensitive to vibrations thanks to fast single shot acquisition and the lack of need for a reference arm for comparison. It allows for a standalone setup compatible with shop floor metrology!
- + At-wavelength sample testing due to its achromatic system embedding up to 4 light sources, automatically controlled by the User Interface.
- + Insensitive to reflections from the back surface of the sample thanks to a unique patent pending method.

 No surface preparation of the sample is needed, avoiding added steps that could disturb the metrology and put the sample at risk.
- + Smart maintenance: On-site user install or replacement of sources with no opening of optical areas and no realignment needed.



SPECIFICATIONS

Optical configuration Mounting configuration Test beam diameters

Optical axis Calibrated range

Working output wavelengths

Output polarization Phase point resolution Minimum exposure time

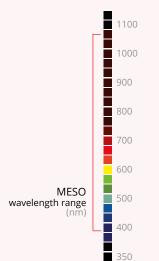
Camera Interface

System software

Warranty

Dimension / Weight Vibration isolation Compressed air Sample reflectivity Sample min. thickness

RMS wavefront repeatability*



double-pass

horizontal or vertical

optical zoom from 1.5" (38.1 mm) up to 6" (152 mm)

4.25" (108 mm) 405 nm to 1064 nm

custom 405 nm, 488 nm, 520 nm, 635 nm, 785 nm, 830 nm, 1064 nm

optional linear, circular

680 x 500 $27 \mu S$

4096 x 3000 pixels, 10 bits

USB 3.0

high performance Dell™ computer & 24″ touchscreen, Windows 10, WaveSurf™ acquisition control & analysis software

1 year system & laser standard, extendable

63 x 30 x 45 cm / 25 kg

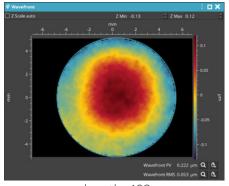
not necessary not necessary

1% - 100%, no attenuation required

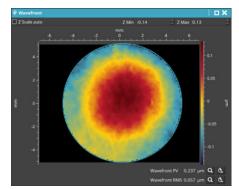
100 μm 1 nm

ACHROMATISM

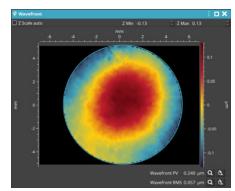
Plane optics measured on Ø4" diameter at 3 wavelengths: wavefront error variation is less than 4 nm RMS ($< \lambda/150$)



wavelength: 402 nm wfe: 53 nm RMS



wavelength: 635 nm wfe: 57 nm RMS



wavelength: 785 nm wfe: 57 nm RMS

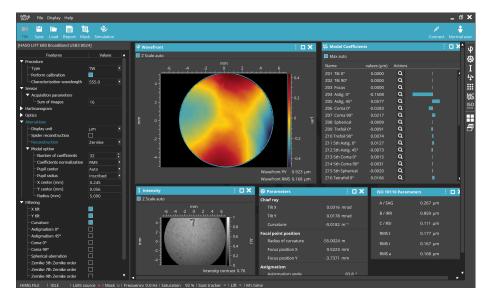
^{*}From a set of 36 measurements on a Ø4" diameter flat mirror, each of them averaged 16 times, a synthetic reference is defined by the mean of the 18 odd measurements. The RMS wavefront repeatability is then defined by the mean RMS difference plus 2x the standard deviation of the difference between the 18 even measurements and the synthetic reference.

SOFTWARE

WAVESURF™

Easy-to-use interface

Wavesurf allows operators and engineers in manufacturing environments to perform wavefront and surface characterization of flat optics and large lenses with just a few clicks. Scripted testing procedures guide users through all the steps. It makes control easy, automated and error-proof.



- + Touchscreen interface control
- + Scripted testing procedures guide the user through all the steps
- + Automated control of up to 4 embedded wavelengths
- + Automated control of test diameter (optical zoom)
- + Complete automated test report
- + ISO10110 standard compliance
- + Data format compatible with CODE V[®] and MetroPro[™]

WHITE PAPERS

- + Shop floor measurement: vibration-proofed solutions for optical metrology
- + At-wavelength metrology for optical systems and surfaces
- + Parallel optics testing: simultaneous characterization of both optical faces in laboratory and manufacturing conditions



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Preliminary .g MESO DATA SHEET